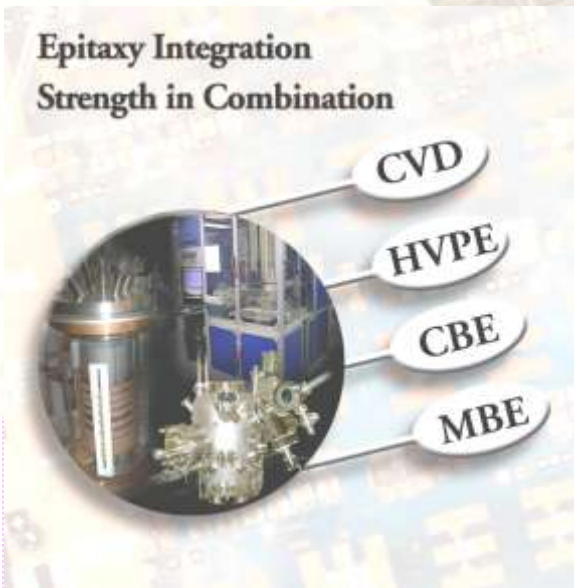


# NexGEN™ Epitaxy Modules for Advanced Materials Devices and Circuits

Let OSEMI's design breakthroughs and our latest state-of-the-art equipment work for you. We are pleased to offer our new fully automated NexGEN™ Epitaxy Systems that allows materials growth integration of MOCVD, MBE, CBE and UHV-CVD Epitaxial Growth. We supply advanced integrated systems with the superb features useful in epitaxial growth.

**Epitaxy Integration  
Strength in Combination**



CVD

HVPE

CBE

MBE

## NexGEN™ Semiconductor Equipment for Research & Development:

- Integrate MOCVD, UHV-CVD, CBE and MBE in one system
- Manual or fully automated systems
- In-situ monitoring of composition
- Perfect for advanced materials including GaAs, GaN, Thick Silicon, Epitaxial Oxides, and other advanced wafers

## NexGEN™ for Production:

- Rapid conversion to from R&D to production using silicon industry style automation
- Efficient 100, 150 & 200mm wafer processing
- Low maintenance cost on multiple small chambers
- Let capacity grow with the market with additional NexGEN™ chambers
- A better option than multi-wafer production for advanced materials

Please contact us to discuss how we can assist you with your equipment needs.

